

In the Claims:

Please amend claim 1 and add new claims 12-19 as follows:

1. (Currently Amended) A vacuum processing apparatus comprising a vacuum chamber, at least one vacuum pump, a pipe connecting said vacuum chamber to said vacuum pump for evacuating said vacuum chamber, a flexible pipe included in a part of said pipe, and a mechanism configured for fixing said vacuum pump so as not to shrink said flexible pipe at the time of evacuation,

said mechanism including:

a floor panel on which said vacuum chamber and said vacuum pump are placed; and

a coupling member which connects said vacuum pump to said floor ~~panel~~ panel so as to prevent shrinkage of said flexible pipe at the time of evacuation.

2. (Previously Presented) A vacuum processing apparatus according to claim 1, wherein said mechanism configured for fixing said vacuum pump so as not to shrink said flexible pipe at the time of evacuation fixes the vacuum pump side of said flexible pipe.

3. (Original) A vacuum processing apparatus according to claim 1, wherein said mechanism is arranged in a pipe extending from said vacuum pump.

4. (Original) A vacuum processing apparatus according to claim 3, wherein said at least one vacuum pump comprises a plurality of vacuum pumps, said mechanism includes a member fixed to the pipes extending upward from said vacuum pumps, and said member is a long member extending over said plurality of the vacuum pumps.

5. (Original) A vacuum processing apparatus according to claim 1, wherein said vacuum chamber includes a device for reading an alignment mark of a substrate in the vacuum.

6. (Original) A vacuum processing apparatus according to claim 5, wherein said substrate comprises a substrate of a display device.

7. (Original) A vacuum processing apparatus according to claim 1, wherein said apparatus is a substrate bonding apparatus of a liquid crystal display device.

8. (Canceled)

9. (Previously Presented) The vacuum processing apparatus as set forth in claim 1, wherein said coupling member is a chain block.

10. (Previously Presented) The vacuum processing apparatus as set forth in claim 1, further comprising an inlet pipe included as part of said connecting pipe and extending from said vacuum pump,

said coupling member connecting between said inlet pipe and said floor panel.

11. (Previously Presented) The vacuum processing apparatus as set forth in claim 1, wherein:

said coupling member connects between a fixing block provided on said floor panel and said vacuum pump; and

said fixing block is provided so that said fixing block and said vacuum chamber sandwich said vacuum pump and face each other.

12. (New) The vacuum processing apparatus as set forth in claim 1, wherein a gap exists between said vacuum pump and said floor panel.

13. (New) The vacuum processing apparatus as set forth in claim 1, further comprising at least one fitting attached to a base frame of said vacuum pump.

14. (New) The vacuum processing apparatus as set forth in claim 13, wherein said base frame and said floor panel are separated from each other by a gap.

15. (New) The vacuum processing apparatus according to claim 1, wherein said flexible pipe is a bellows-like pipe.

16. (New) The vacuum processing apparatus according to claim 1, wherein said coupling member is fixed to said floor panel so as to be opposite to said vacuum chamber.

17. (New) The vacuum processing apparatus according to claim 1, further comprising a cushion member, provided between said vacuum pump and said floor panel.

18. (New) The vacuum processing apparatus according to claim 1, further comprising a coating layer, provided on a surface of said flexible pipe so as to suppress vibration of said flexible pipe.

19. (New) The vacuum processing apparatus according to claim 18, wherein said coating layer is made of either rubber or resin material.